# **Special Issue**

## **MOEMS: Micro-Optical MEMS**

## Message from the Guest Editors

Optical microelectromechanical systems (MEMS), microoptoelectromechanical systems (MOEMS), or optical microsystems are integrated devices or systems that interact with light through actuation or sensing at a micro- or millimeter scale. The multidisciplinary nature of the field has allowed for the collaboration of researchers with a very diverse background and enabled a rapid technological growth that has resulted in enormous commercial success in imaging, laser scanners, and optical communications. In this Special Issue, the current state of this exciting research field will be presented, covering a wide range of topics, including but not limited to:

#### **Guest Editors**

Dr. Nelson Sepulveda

Department of Electrical and Computer Engineering, Michigan State University, East Lansing, MI 48824™1226, USA

Dr. Jing Wang

Department of Electrical Engineering, University of South Florida, Tampa, FL 33620, USA

### Deadline for manuscript submissions

closed (31 December 2020)



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Micromachines
Editorial Office
MDPI, Grosspeteranlage 5
4052 Basel, Switzerland
Tel: +41 61 683 77 34
micromachines@mdpi.com

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#### Editor-in-Chief

Prof. Dr. Ai-Qun Liu

Department of Electrical and Electronic Engineering, The Hong Kong Polytechnic University, Hong Kong, China

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